

10/588698

Atty. Dkt. No. 039262-0156

AP20 Rec'd PCT/PTO 08 AUG 2006

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Tadahiro OHMI, et al

Title: METHOD OF MANUFACTURING A SEMICONDUCTOR
DEVICE AND METHOD OF ETCHING AN INSULATING FILM

Appl. No.: Unassigned

International Filing Date: 02/02/2005
371(c) Date: 08/08/2006

Examiner: Unassigned

Art Unit: Unassigned

PRELIMINARY AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Prior to examination of the present Application, Applicant respectfully requests that the application be amended as follows:

Amendments to the Specification begin on page 2 of this document.

Amendments to the Claims are reflected in the listing of claims which begins on page 3 of this document.

Remarks/Arguments begin on page 8 of this document.

Please amend the application as follows: